

# Dual Chamber Electron Beam Evaporation System

## Model: SA-VKE500D

SA-VKE500D is a research-grade electron beam evaporation platform. Featuring an interworking dual-chamber loadlock design where the upper and lower cavities serve as mutual loadlock units, it overcomes the technical bottleneck of loadlock integration for evaporators. The system fully meets process requirements for medium-small batch production and advanced experimental research platforms.



### Feature

- Low cost
- Lift-off
- Co-deposition
- High evaporation rate

### Application

- Laser
- R&D
- Integrated circuit
- MEMS

### Specifications:

| Parameter                   | Descriptions                                                                    |
|-----------------------------|---------------------------------------------------------------------------------|
| Number of Crucibles         | 6(max.)                                                                         |
| Automatic Loadlocks         | Single & multi-chip automatic loadlock                                          |
| Workpiece Angle             | -45°~45°, adjustable                                                            |
| Power Supply                | 10kW(max.)                                                                      |
| Film thickness monitoring   | Crystal oscillator controller                                                   |
| Ion Source                  | Kaufman & Hall ion source                                                       |
| Fixture types               | Dome & Planetary                                                                |
| Pumping System              | Cryopump / magnetically levitated turbo-molecular pump<br>+ Dry mechanical pump |
| Coating Uniformity          | ±2%                                                                             |
| Coating Repeatability       | ±2%                                                                             |
| Uniform Deposition Area     | Ø260 mm(max.)                                                                   |
| Ultimate Vacuum             | 1E-5Pa                                                                          |
| Vacuum Measurement          | Full-range vacuum gauge                                                         |
| Temperature Control Range   | RT~500℃                                                                         |
| Space Requirements(L×W×H,m) | 3×2.5×2.2                                                                       |

**Principle:**

